

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

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**REQUEST FOR CERTIFICATE OF  
CORRECTION PURSUANT TO  
37 C.F.R. § 1.322**Docket Number:  
**10191/2169**Conf. No.:  
**8531**

Application Number <b>10/031,842</b>	Filing Date <b>June 10, 2002</b>	Examiner <b>Shamim Ahmed</b>	Art Unit <b>1765</b>
Patent Number <b>6,899,817</b>	Issue Date <b>May 31, 2005</b>		
Invention Title <b>DEVICE AND METHOD FOR ETCHING A SUBSTRATE USING AN INDUCTIVELY COUPLED PLASMA</b>	Inventor(s) <b>Volker BECKER et al.</b>		

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to : Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on:

Date: 1/6/06Signature: R. Messina

We have compared the above patent with the application as filed and have found errors in the printing of the patent. We respectfully request that the enclosed Certificate of Correction on Form PTO-1050 be issued correcting the mistakes set forth therein under authority of 35 U.S.C. §254. The exact column and line number where the errors occur in the patent are listed on the enclosed certificate.

The errors that appear in this patent are Patent Office errors and no fee is believed required. However, if necessary, please charge any fee or credit any overpayment to Deposit Account No. 11-0600.

Dated: 1/6/06

By:

  
Gerard A. Messina, Reg. No. 35,952

*Certificate*  
JAN 18 2006  
*of Correction*

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JAN 18 2006

UNITED STATES PATENT AND TRADEMARK OFFICE  
**CERTIFICATE OF CORRECTION**

**PATENT No.** : 6,899,817

**DATED** : May 31, 2005

**INVENTOR(S):** Volker BECKER et al

**It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:**

On the face of the patent, # (57) Abstract, line 1, change “A method and a suitable device for carrying out this method” to “A method and a device is for--

On the face of the patent, # (57) Abstract, line 2, delete “is proposed, for”

On the face of the patent, # (57) Abstract, line 2, change “a substrate (18), especially a silicon” to --a substrate, e.g., a silicon--

On the face of the patent, # (57) Abstract, line 3, change “plasma (14).” to --plasma--

On the face of the patent, # (57) Abstract, line 6, delete “(14)”

On the face of the patent, # (57) Abstract, line 6, change “a reactor (15).” to --a reactor.--

On the face of the patent, # (57) Abstract, line 10, change “in particular” to --such as--

On the face of the patent, # (57) Abstract, line 10, delete “(21)”

On the face of the patent, # (57) Abstract, line 12, delete “(10)”

On the face of the patent, # (57) Abstract, line 12, change “ICP source (13). For this” to --ICP source.--

On the face of the patent, # (57) Abstract, line 13, change “the magnetic field” to --The magnetic field--

On the face of the patent, # (57) Abstract, line 15, delete “(10)”

On the face of the patent, # (57) Abstract, line 16, change “plasma (14).” to --plasma--

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New York, NY 10004

**Patent No. 6,899,817 B1**

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